

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Application of | : | Customer Number: 20277 |
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| Toshihiko TANAKA | : | Confirmation Number: 3832 |
| | : | |
| Application No.: 10/551,553 | : | Group Art Unit: 2812 |
| | : | |
| Filed: October 03, 2005 | : | Examiner: JELSMA, Jonathan G. |
| | : | |
| For: PROCESS FOR FABRICATING SEMICONDUCTOR DEVICE AND METHOD FOR GENERATING MASK PATTERN DATA | | |

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the non-final Office Action dated March 17, 2009 having a three-month shortened statutory period for response set to expire June 17, 2009, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper. This listing of claims replaces all prior versions, and listings, of claims in the application.

Remarks begin on page 4 of this paper.